

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:	)	
	:	Examiner: M. Seth
Takenobu KOBAYASHI et al.	)	
	:	Group Art Unit: 2624
Application No.: 10/777,192	)	
	:	Confirmation No.: 7532
Filed: February 13, 2004	)	
	:	
For: SURFACE POSITION MEASURING METHOD )		February 26, 2009
AND APPARATUS	:	

**Mail Stop Amendment**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

AMENDMENT

Sir:

In response to the Office Action dated November 26, 2008, please amend the above-identified application as follows: